

NanoImprint Systems



UV Type / Thermal Curing Type

Supports 300mm wafer and is best used as an alternative patterning for lithography. Also good for tera bite light disk, LED, micro lens, diffusion film, high concentrated package, and etc

Hsd s wedge error system, pressurization, UV exposure, demolding, high-accuracy repetitive positioning,

Best for R&D and Mass production.

Other features include:

- UV-type and Thermal-curing-type Nanoimprint Systems
- Applications Include Microlenses, Diffusion Films, and High-density Packages
- Compatible with Wafers up to 200mm and Can Mount Metal Mold and Resin Mold
- Parallelism of UV Irradiation Maintained using three piezo elements
(CHA=1.5 degrees, DA=0.5 degree with distribution less than +/-5 percent)

<Structure>

- 1.XY axis Air Slide
- 2.Linear Motor
- 3.Linear Gage
- 4.Z axis Air Slider
- 5.Wedge error system
- 6.Micro Dispenser
- 7.Auto Focus Board
- 8.Substrate holder
- 9.Metallic holder
- 10.UV exposure unit
- 11.Air conditioning system